

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A fabricating method of a plasma display panel, comprising
~~the steps of:~~

providing a sheet into which a black material layer and an electrode material layer are integrated;

forming the sheet on a substrate;

aligning a first mask on the front surface of a substrate where the sheet has been formed and exposing the sheet;

aligning a second mask on the rear surface of the substrate and exposing the sheet;

and

developing the exposed sheet to form a bus electrode and a light shielding layer.

2. (Currently Amended) The fabricating method according to claim 1, wherein the step of developing the exposed sheet includes the step of:

developing the black ~~matrix~~ material layer and the electrode material layer at the same time.

3. (Original) The fabricating method according to claim 2, wherein the exposure using the first mask is made by use of an ultraviolet ray of around 200~800mmJ/cm³.

4. (Original) The fabricating method according to claim 2, wherein the exposure using the second mask is made by use of an ultraviolet ray of around 400~1000mmJ/cm³.

5. (Original) The fabricating method according to claim 1, wherein the bus electrode is formed of the black material layer and the electrode material layer.

6. (Currently Amended) The fabricating method according to claim 5, wherein the black material layer includes ~~at least one of~~ ruthenium Ru and Cobalt Co of 50~60%, solvent of 20~30% and photosensitive resin of 25~35%.

7. (Original) The fabricating method according to claim 5, wherein the electrode material layer includes silver Ag of 50~60%, solvent of 20~30% and photosensitive resin of 25~35%.

8. (Currently Amended) The fabricating method according to claim 1, further comprising ~~the steps of~~

forming a dielectric body on the substrate on which the bus electrode and ~~the a~~
black matrix have been formed; and

forming a protective film on the substrate on which the dielectric body has been
formed.

9. (Currently Amended) The fabricating method according to claim 1, wherein ~~the~~
~~step of~~ providing the sheet includes ~~the step of~~:

joining the black material layer with the electrode material layer in a laminating
process.

10. (Currently Amended) The fabricating method according to claim 1, wherein ~~the~~
~~step of~~ forming the sheet on the substrate includes ~~the step of~~:

joining the substrate with the sheet in a laminating process.

11. (Currently Amended) A fabricating method of a plasma display panel, comprising
~~the steps of~~:

providing a sheet into which a black material layer and an electrode material layer
are integrated;

forming the sheet on a substrate;

exposing the sheet by use of the first and second masks and developing the sheet to form a bus electrode and a light shielding layer.

12. (Currently Amended) The fabricating method according to claim 11, wherein the step of forming the bus electrode and the light shielding layer includes the steps of:

exposing the electrode material layer and the black material layer of the sheet by use of the first mask, and at the same time exposing the black material layer of the sheet by use of the second mask; and
developing the black material layer and the electrode material layer of the exposed sheet simultaneously.

13. (New) The fabrication method according to claim 1, wherein the light shielding layer is formed from a portion of the black material layer.

14. (New) The fabrication method according to claim 2, wherein the black matrix is formed from the black material layer.

15. (New) A display fabricating method, comprising:
 - attaching a prefabricated layer to a substrate, wherein the prefabricated layer comprises a black material layer and an electrode layer;
 - forming at least one electrode using the black material and electrode layers of the prefabricated layer; and
 - forming at least one black matrix using the black material of the prefabricated layer.
16. (New) The method of claim 15, wherein the electrode is formed by exposing the prefabricated layer through a first mask on a front surface of the substrate.
17. (New) The method of claim 16, wherein the black matrix is formed by exposing the prefabricated layer through a second mask on a rear surface of the substrate.
18. (New) The method of claim 15, wherein the black material layer includes ruthenium Ru and cobalt Co of 50~60%, solvent of 20~30% and photosensitive resin of 25~35%.
19. (New) The method of claim 15, wherein the electrode layer includes silver Ag of 50~60%, solvent of 20~30% and photosensitive resin of 25~35%.

20. (New) The method of claim 15, wherein the prefabricated layer is attached to the substrate with at least one of a temperature around 50 ~ 80°C and pressure around 1.5Kg/cm².
21. (New) The method of claim 15, wherein the prefabricated layer is formed by laminating the black material layer and the electrode layer.
22. (New) The method of claim 21, wherein the lamination occurs in at least one of temperature around 70 ~ 90°C and pressure around 3 ~ 4 Kg/cm².
23. (New) A display fabricating method, comprising:
 - forming at least one black material layer and at least one electrode material layer on a substrate;
 - aligning a first mask with a first side of the substrate and exposing the black and electrode material layers; and
 - aligning a second mask with a second side of the substrate and exposing the electrode material layer, wherein the first and second sides of the substrate are opposite sides.